D egradation of LaM nO $_{3 v}$ surface layer in LaM nO $_{3 v}$ / m etal interface

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W e report electricalm easurem ents show ing the degradation processes of LaM nO_{3 y} (LaM nO) in LaM nO /norm alm etal interface in both point contact and planar-type junctions. Im – m ediately after the preparation of the interface, the degradation process was followed by m easuring the evolution of the junction resistance versus time. This process is characterized by the appearance of a second m axim um in the resistance vs. tem perature (R-T) dependence at tem peratures lower than the C unie tem perature T_c, at which the m etal-insulator transition occurs in the bulk. These e ects are explained in term s of the form ation of a depleted interface layer in LaM nO caused by an out-di usion of oxygen from the m anganite surface to the norm alm etal. This assumption is con rm ed by X P S m easurem ent. Sim ilar results on LaSrM nO_{3 y} interfaces are also obtained.

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The m aquetoresistive rare earth perovskites $La_1 _xA_xM nO_3 _y$ (LaAM nO, A=Ca, Sr, Pb), which include LaM nO, have been in the research spotlight for a decade. Optim ally doped LaAM nO exhibits a param agnetic - insulating behavior above the Curie tem perature T_c and a ferrom agnetic -m etallic behavior below Tc. In the recent years, the giant m agnetoresistance phenomenon (MR) has been intensively studied in these materials. However till low - eld, MR e ects in granular In s and tunneling of spin-polarized electrons through an insulating barrier in LaAM nO /Insulator/LaAM nO m agnetic tunnel junctions (M T J) gave prom ise to their technological applications like magnetic eld sensor and

nonvolatile m agnetic random access m em ory. O ne can expect a near 100% value of tunneling m agnetoresistance (TMR) in tunnel junctions based on half m etallic LaAM nO ferrom agnet. TMR depends on the quality of the m agnetic state of the LaAM nO surface, interface quality, surface roughness of the electrodes, etc. A nom abus tunneling behavior observed in M T J could be explained by extrinsic factors playing a dom inant role in the M T J interfaces. This assumption has been m ade by several authors. Park et al.¹ show ed that even in a fully oxidized LaSrM nO sample, the m agnetic properties at the

surface boundary are signi cantly di erent from those of the bulk. In addition, several experiments indicated the creation of an oxygen depleted layer of LaAM n0 interfaces. M ieville et al.² studied the interface resistance and transport across conducting ferrom agnetic oxide/m etal interfaces. They measured a very high resistance of LaSrMnO/Al(Nb) junctions, which could be explained by the existence of a degraded surface layer of ferrom agnetic oxide due to a loss of oxygen. A lso de Teresa et al.3 observed a dependence of TMR on the type of tunneling barrier. The present work was stimulated by the above m entioned results, but m ainly by the results published in our previous paper4. LaM nO /A ½O 3/Nb junctions were fabricated for the study of the in uence of illum ination on the electrical properties of M T J. The A b O 3 insulating barrier was prepared using well-known thin lm s N b technology⁵: An alum inium thin lm was sputtered on LaM nO , and then oxidized in an oxygen atm osphere. Finally a sem i-transparent Nb upper electrode was sputtered on the top. Using the same technique with the same preparation parameters, the width of the barrier created on the LaM nO was about two times higher than that for Nb/A $\frac{1}{2}O_3$ /Nb junctions.

In this paper we study the LaM nO surface properties in contact with Al, In, Au and Pb m etals in order to explain the physical processes in the interface which give rise to an unusual behavior of M T J. The LaM nO /norm al m etal point contact exhibits a change of resistance im – m ediately after its preparation. In the planar junctions (m ore stable than point contact) the appearance of a second m axim um in the R-T dependence was observed several hours after junction preparation. These e ects are explained by an out-di usion of oxygen from LaM nO, and they were con rm ed by XPS spectroscopy.

200 nm thick LaM nO epitaxialthin lm swith T_c= 270 K were deposited on single crystalline SrT iO₃ substrates by low pressure liquid source metal-organic chemical vapour deposition $(M \circ C \vee D)^6$. LaM nO/metal point contacts were realized using a holder which exerted a constant pressure of the tip onto the sample. Bulk Au, Al, or Pb were used for the upper electrode. The shape

of the sharp point was prepared by m echanical sharpening. A fler the electrical measurements, a 200x200 $\,$ m² geometric area was evaluated for the Pb tip.

For the preparation of planar junctions, a 40 m -wide and 260 m - long LaM nO₃ base electrode was formed by wet etching through resist mask. A fler stripping the photoresist, the area for deposition of next layers by lifto technique was de ned in positive photoresist. Shortly before the deposition of the barrier and the upper electrodes, the surface of LaM nO₃ was etched to eliminate a contaminated and degraded upper layer. A 100 nm thick Al or In layer was deposited by them al evaporation. Junctions with an area of 40 40 m² were nalized after the rem oval of the photoresist.

The R-T and resistance vs. time (R-t) characteristics were measured by a computer controlled four point m ethod .

XPS spectra were obtained in an ESCALAB 210 spectrom eter that consisted of two separate independentlypum ped cham bers. P ressures in the range of 6×10^{-11} m bar and 10 ⁸ m bar were obtained in the analysis and preparation chambers, respectively. Alhas been evaporated in the analysis chamber from a resistively heated 1am ent m ade of A lw ire w rapped around a thick tungsten wire. The power was maintained to give a reproducible evaporation rate of 1 m onolayer of A lper m inute. C ontrol evaporation carried out onto a clean Au foil showed that under our experim ental conditions, only m etallic A l is evaporated, maintaining this oxidation state throughout all the acquisition time. A hem ispherical electron energy analyser working in the pass energy constant mode at a value of 50 eV was used. U nm on och rom at ized A 1K a radiation was used as the excitation source. Spectra were energy-calibrated by taking the La3d5/2 peak at 834.6 eV (BE). The spectra were acquired at 90 (norm al) and 20 (grazing) degrees with respect to sam ple surface.

In Fig 1, the LaM nO /m etal point contact resistance dependence versus time shows a signi cant increase at several hundred seconds after the preparation of the contact. These changes were observed even if noble m etal (Au) was used as the upper electrode m aterial. Similar results on high-T_c superconductors (HTS) were described in our previous work⁷. The change of the point contact resistance was explained within an oxygen out-di usion m odel.

The total point contact resistance with a tip made of nonreactive metal (e.g. Au) can be expressed as $R = R_M + R_{LaM n0} + R_T$, where R_T is the tunneling resistance and R_M and $R_{LaM n0}$ the contact resistances with m etal and LaM n0, respectively. We suppose that R_M and R_T are constant in time for stable nonreactive m etals, and the change of resistance R is then given by the change of $R_{LaM n0}$. The creation of additional barriers from a LaM n0 oxygen depleted layer as well as from the oxide of the upper metallic electrode (created from reactive m etal like Al, Pb) creates a complex interface. But in all cases, the Curie tem perature T_c in the LaM n0 oxygen depleted also.

In the next measurements the planar junctions were used because they were more stable than the point contact ones. Because A lis a very reactive m etalw ith a very short time of interaction, indium as an upper electrode was used for the following measurement. The R-T characteristic m easured on a LaM nO /In planar junction at di erent tim es (3, 5 and 23 hours) after preparation of the contacts is shown in Fig 2. We observed the classical maximum correlated with the I-M transition of the bulk m aterial at T_c around 275 K of the bulk m aterial. This maximum did not change very much with time. It means that the oxygen content in the bulk material does not change. A fter a long tim e (23 hours) a second m axim um appears around T $'_{c}$ = 185 K in the R-T characteristics. We know that in LaAM nO system s the T c decreases with a decrease of the oxygen content, and it disappears for deoxygenated sam ples that exhibit sem iconducting properties. This new maximum is related to the oxygen depleted interface, and it is broader due to a distribution of T'_{c} . This value of T'_{c} = 185 K corresponds to an average oxygen content at the interface of y around $0.1.^{8}$

To con m the occurrence of out-di usion processes in the LaM nO surface layer, XPS measurements of LaM nO /A linterfaces were studied. Fig.3 showns spectra of the O 1s, M n2p, A l2p and La3d regions measured on clean (original) LaM nO surface (curves a) at the norm al acquisition angle, after the deposition of around 1 m onolayer of A 1 (curves b), at the norm al adquisition angle, around 2 m onolayers of A l, at the norm al adquisition angle (curves c), and curves d were measured as curves c at a grazing adquisition angle. O ne can see the following features in the XPS spectra after the deposition of A l: - two peaks correlated with A l and A $\frac{1}{2}O_3$,

- two peaks in the 01s spectra correlated with oxygen bonding in LaM nO₃ at 529.9 eV and A \downarrow O₃ at 531.6 eV, - shift of the peaks in the M n2p spectra due to the decreasing of M n valency.

The deposition of the rst monolayer of Al on the LaM nO surface provokes the oxidation of Al to Al³⁺, whose peak arises at about 75 eV (BE). This behaviour was tested by a simultaneous deposition of Al on Au. The detection of metallic Alduring the whole experiment (more than 1 hour) exclude the oxidation of Aldue to the residualO₂ partial preasure in the analytic chamber. In additional, when a second amount of Alwas deposited (curve c in Fig.3a), most of it remained metallic (peak at 72.6 eV BE). Finally, when this situation is examined at the grazing adquisition angle (curve d in Fig.3a), the relative intensity of the peak from Al(0), in comparison with that from Al⁺³, increases substantially, indicating that metallic Al is located on the top of the AlgO₃.

The oxidation of A l in the LaM nO $_3/A$ l interface accompanying the appearence of two peaks in the O ls spectra is correlated with a change of binding energy due to the creation of A $_2O_3$. The sm ooth second peak wasm easured also on clean LaM nO surface (curve a in Fig.3c) as wellas after cleaning treatment. The origin of the second peak can be explained by the contam ination of LaM nO

by CO_3^- species within the preparation procedure of the LaM nO thin lm. Anyway, the intensity of the peak at the energy of 520.6 eV increase after the deposition of Al (curves b and c in Fig.3c) due to the arising of O^- ions in A $\frac{1}{2}O_3$. The m easurem ent at the grazing angle shows that A $\frac{1}{2}O_3$ is created on the LaM nO surface (the global intensity of A l2p signal grows and the M n and La signals decrease). These facts as b indicate the existence of m etallic A l on the top of A $\frac{1}{2}O_3$.

A signi cant chem ical shift of M n2p peak from 642.5 eV before A levaporation to 641.4 eV after A levaporation strongly indicates a decrease of M n valency to + 3 state with a subsequent change of the M n³⁺ /M n⁴⁺ ratio, typical for oxygen-de cient LaAM nO.

From XPS measurements described above, we can con m the loss of oxygen from the LaMnO in the LaMnO/Al interface and the creation of a LaMnO/Al_D_3/Al_junction with a subsequent change in the Mn³⁺/Mn⁴⁺ ratio.

In conclusion, we presented R-T and R-t m easurements on LaM nO /m etal point contact and planar junctions. The time evolution of point contact junction resistance as wellan arising of a second peak on the R-T characteristics were observed. These e ects were explained in terms of the formation of a depleted interface layer in LaM nO_{3 x} caused by the out-di usion of oxygen from the manganite surface to the normal metal. This assumption was con-

rm ed by XPS m easurem ents. The similar results (XPS as well as time evolution of point contact resistance) on LaSrM nO m agnetoresistive thin lm swere also obtained.

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1.2 JPb LaMn03 R/R₀ [a.u.] LaMnO3/A 1.1 LaMnO_{3-x}/Au - 3-x 0000000 1.0 500 1000 1500 2000 0 Time [sec.]

FIG.1. Time evolution of the LaM nO /m etal (Au - open circles, Al-solid squares and Pb - solid circles) point contact resistance. The m easurem ent was started im m ediately after the point contact preparation.

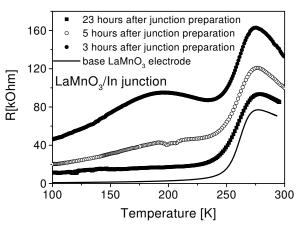


FIG.2. R-T dependence of the LaM nO electrode (solid line) and R_T -T dependence of LaM nO/In planar junction m easured 3 hours (solid squares), 5 hours (open circles) and 23 hours (solid circles) after the deposition of the In upper electrode.

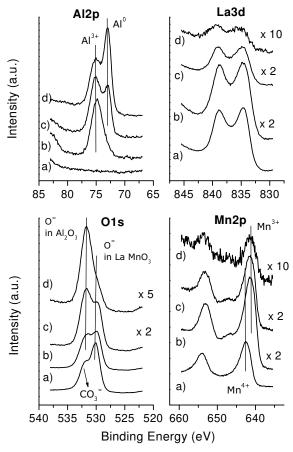


FIG.3.

XPS spectra of the Ols, Mn2p, Al2p and La3d regions measured on the clean surface of LaMnO (curves a) after the deposition of one monolayer and two monolayers of Al, at the norm al adquisition angle (curves b and c, respectively) and the same that curves c, at the grazing adquisition angle.